

ELECTRONIC INFORMATION DISCLOSURE STATEMENT

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Title of Invention

METHOD FOR REACTIVE ION ETCH PROCESSING OF A
DUAL DAMASCENE STRUCTURE

Application Number :

Confirmation Number:

First Named Applicant: William America

Attorney Docket Number: FIS920040053US1

Art Unit:

Examiner:

Search string: (6479391 or 6514852 or 6573176 or 6576482).pn

US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
	1	6479391	2002-11-12	Morrow et al			
	2	6514852	2003-02-04	Usami			
	3	6573176	2003-06-03	Hong			
	4	6576482	2003-06-10	Aggarwal et al			

Signature

Examiner Name	Date